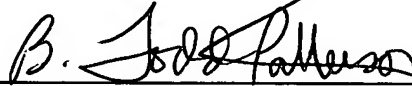


The patents and/or publications submitted herewith are set forth on the attached Form PTO-1449.

If the sum of \$180.00 is due under 37 CFR § 1.17(p) pursuant to § 1.97, the Commissioner is hereby authorized to charge this fee, and any other fee necessary to make this submission timely, to the Deposit Account No. 20-0782/AMAT/8539/BTP.

Respectfully submitted,

A handwritten signature in black ink, appearing to read "B. Todd Patterson", is written over a horizontal line.

B. Todd Patterson
Registration No. 37,906
MOSER, PATTERSON & SHERIDAN, L.L.P.
3040 Post Oak Blvd. Suite 1500
Houston, TX 77056
Telephone: (713) 623-4844
Facsimile: (713) 623-4846
Attorney for Applicant(s)

U.S. Department of Commerce, Patent and Trademark Office		Docket No.	Serial No.
(PTO Form 1449 modified)		APPM/8539	Unassigned
INFORMATION DISCLOSURE STATEMENT BY APPLICANT		Applicant Kim, et al.	Confirmation No. Unknown
(Use several sheets if necessary)		Filing Date	Group
	Examiner Unknown	Herewith	Unknown

U.S. Patent Documents

*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
	A1	6,544,900	04/08/2003	Raaijmakers, et al.	H01L	2131	11/14/2001
	A2	6,458,718	10/01/2002	Todd	438	778	04/24/2001
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	B1	1 150 345	10/31/2001	EP	H01L	21/316	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B2	2001-189312	05/02/2001	JP	C30B	25/02	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B3	63062313	03/18/1988	JP (abstract)	H01L	21/203	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B4	58098917	06/13/1983	JP	H01L	21/205	<input type="checkbox"/>	<input checked="" type="checkbox"/>

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	C1	Lee, et al., <i>Cyclic technique for the enhancement of highly oriented diamond film growth</i> , Elsevier Science S.A., Thin Solid Films (1997) 264-268.
	C2	Choi, et al., <i>Stability of TiB₂ as a Diffusion Barrier on Silicon</i> . Electrochemical Society Vol. 138 No. 10 October 1991.

Examiner

Date Considered

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(Use several sheets if necessary)					Filing Date		Group	
Examiner Unknown					Herewith		Unknown	
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	B7	2001-111000	04/20/2001	JP	H01L	27/105	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B8	5102189	04/23/1993	JP	H01L	21/336	<input type="checkbox"/>	<input checked="" type="checkbox"/>
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	C3	Paranjpe, et al., <i>Atomic Layer Deposition of AlO_x for Thin Film Head Gap Applications</i> , ECS, Journal of the Electrochemical Society, 148 (9) G465-G471 (2001).						
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Examiner Unknown					Herewith		Unknown	
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	A22	2003/0082300	05/01/2003	Todd, et al.	427	255.27	02/11/2002	
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	A29	2002/0093042	07/18/2002	Oh, et al.	257	303	11/13/2001	
	A29	2001/0055672	12/27/2001	Todd	428	212	02/07/2001	
	A30	2001/0046567	11/29/2001	Matsuki, et al.	427	578	04/06/2001	
	A31	2001/0024871	09/27/2001	Yagi	438	604	01/31/2001	
	A32	2001/0020712	09/13/2001	Raaijmakers, et al.	257	301	01/18/2001	
Foreign Patent Documents								
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	B6	2001-189312	07/10/2001	JP	H01L	21/316	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B7	2001-111000	04/20/2001	JP	H01L	27/105	<input type="checkbox"/>	<input checked="" type="checkbox"/>
OTHER ART								
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	C3							
	C4							
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